



**SUPPLEMENTAL INFORMATION CITED BY APPLICANTS THAT MAY BE MATERIAL
TO THE PROSECUTION OF THE SUBJECT APPLICATION**

Applicants: F.M. Schellenberg et al. Attorney Docket No.: MEGC122529
Application No.: 10/811,418 Art Unit: 2825 / Confirmation No.: 2647
Filed: March 26, 2004 Examiner: Binh C. Tat
Title: CREATING PHOTOLITHOGRAPHIC MASKS

U.S. PATENT DOCUMENTS

*Examiner	Cite Initials	Cite No.	Document No.	Kind Code	Date (mm/dd/yyyy)	Name
<u>BC</u>		U16	6,416,907	B1	07/09/2002	Winder et al.
<u>BC</u>		U17	6,620,561	B2	09/16/2003	Winder et al.

FOREIGN PATENT DOCUMENTS

*Examiner	Cite Initial	Cite No.	Document No.	Kind Code	Publication Date (mm/dd/yyyy)	Country	English Provided	Abstract Provided	Translation Provided

None

OTHER INFORMATION
(Including Author, Title, Date, Pertinent Pages, Etc.)

*Examiner	Cite Initial	Cite No.

None

Examiner

Date Considered

01/15/06

*Examiner: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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